

ABSTRACT OF THE DISCLOSURE

Methods of forming microlens structure are provided. A hard mask is formed overlying a transparent material. An opening is patterned into the hard mask. Both the patterned hard mask and the underlying transparent material are exposed to a wet etch that etches the hard mask and the transparent material. As the hard mask is etched the opening increases exposing more of the transparent material. Depending on the etch selectivity, a lens shape is formed with sloped sidewalls. The lens opening may be filled with lens material to form a lens.

10